

DEVICE FOR INSPECTING PROBE CARD

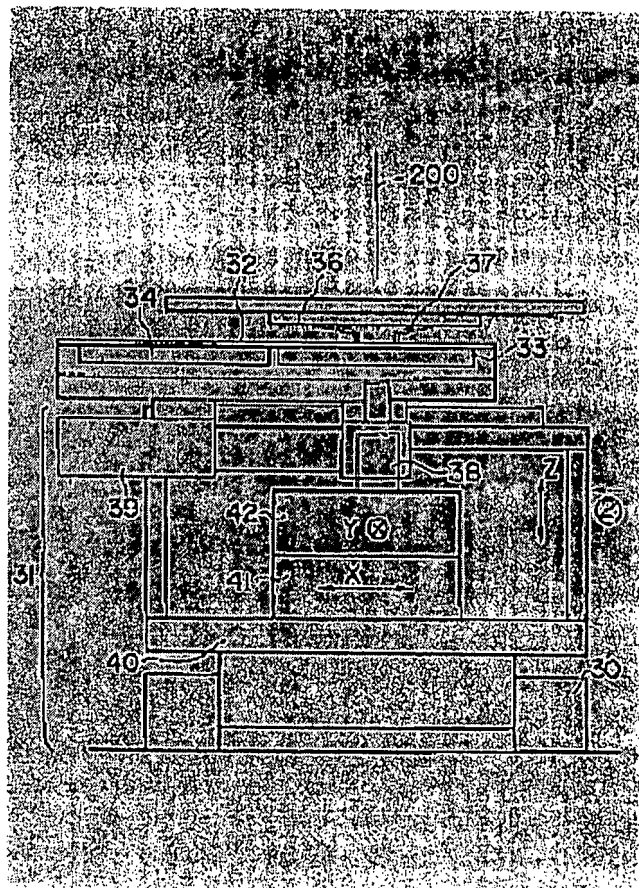
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Abstract of JP5157790

PURPOSE: To inspect the variation in height, contact resistance and the coordinate pattern of the point of the measuring needle of a probe card quickly and very accurately.

CONSTITUTION: An elevating unit 31 is so supported as to move up and down by the base 30 of an inspecting device, and a combined inspection board 32 is fixed on the unit 31. The board 32 can be slid in the unit 31, an electrode plate 33 made of conductor and a transparent glass plate 34 are parallelly provided on the same plane, and either of the plates 33 and 34 can be made to face an inspecting position 200. A probe card 36 is located above the board 32 and held by a probe card holder, and the measuring needle 37 of the card 36 and the plate 33 are connected to a tester. A device for observing the needle point consisting of an optical microscope 38 and a CCD camera 39 is provided movably in X and Y directions in the unit 31, and the image of the point of the needle 37 through the plate 34 is recognized. Therefore, various inspections can be continuously carried out by sliding the board 32.



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